

<b>Notice of References Cited</b>	Application/Control No. 09/921,555	Applicant(s)/Patent Under Reexamination UEDA ET AL.	
	Examiner Michael Kornakov	Art Unit 1746	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

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	U	Handbook of semiconductor wafer cleaning technology. Edited by W.Kern, 1993 by Noyes Publications, pages 3, 137-141
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	X	Menon, V.B. and Donovan, R.P. Microcontamination, 8(11):29-34

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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